



Attorney Docket: 029368.50324US  
PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: SHINCHIRO YAGI  
Serial No.: 09/914,044 Group Art Unit: 2851  
Filed: DECEMBER 11, 2001 Examiner: Fuller, Rodney Evan  
Title: INSPECTION OBJECT SILICON WAFER FOR THE PURPOSE  
OF DETECTING CRYSTAL DEFECTS AND THE METHOD OF  
DETECTING THEREOF

PETITION FOR EXTENSION OF TIME UNDER 37 C.F.R. 1.136(a)

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Applicant hereby requests that the period to take action in the above-captioned application be extended by one month pursuant to the provisions of 37 C.F.R. 1.136(a).

A check in the amount of \$110.00 is submitted herewith in payment of the required extension fee. This amount is believed to be correct, however, the Commissioner is hereby authorized to charge any deficiency, or credit any overpayment, to Deposit Account No. 05-1323 (Docket #029368.50324US).

November 5, 2003

11/06/2003 AADD01 00000052 09914044

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Respectfully submitted,

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